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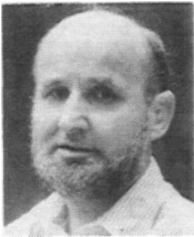
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Dr. Spiller has written book chapters on "X-Ray Lithography" (*Topics in Applied Physics*, Vol. 22, Springer-Verlag, 1977) and "Soft X-Ray Optics and Microscopy" (*Handbook on Synchrotron Radiation*, North-Holland, 1983), organized a conference on "High-Resolution X-Ray Optics" (Proc. SPIE 316, 1981), and given numerous invited talks and lectures on topics in x-ray optics. He is a fellow of the Optical Society of America and the American Association for the Advancement of Science, and a member of the Deutsche Physikalische Gesellschaft and SPIE.